SMARPROBE *LX*

SmarAct develops high-performance solutions for handling and positioning in the micro- and nanometer range. The broad product portfolio - from single stages to complex parallel kinematics, miniaturized robots and easy-to-use control systems - is completed by sophisticated measuring equipment based on powerful laser interferometers.

We serve high accuracy positioning and metrology applications in research and industry within such fields as optics, life sciences, micro-assembly, semiconductors and microscopy. Maintaining the complete production in house allows a high level of customization.

Thus, we always provide you with the optimal individual or OEM solution.

Headquarters

SmarAct GmbH

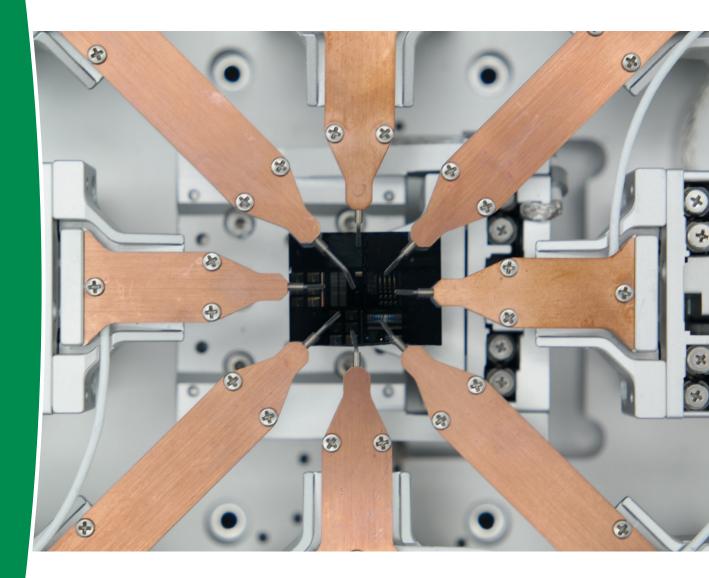
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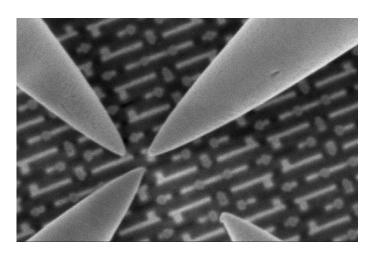




The High Precision Platform for Nanoprobing Tasks

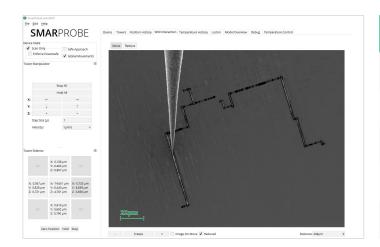
For high precision matters.

KEY FEATURES



Exceptional performance Closed-loop control with 1 nm resolution Full area probing on 25 mm x 25 mm Low thermal drift and large scan range Low noise in-situ current (EBAC) amplifier

Autotouch function



Easy to use
"Point&Click" and joystick control
Group movements and "Step&Repeat"
CAD navigation possible
Automatic landing of all probes
Stable contact even on 7nm transistors



Fully configurable
Retrofit to most SEMs
Use with an optical microscope
Customizable to application
Optional heating/cooling sample stage
Etching station for probe production

VISIT WWW.SMARACT.COM/NANO-PROBING TO GET MORE INFORMATION.

SYSTEM DESCRIPTION

The probe-station SMARPROBE allows the active temperature control for low thermal positioning of up to eight probes to analyze drift (L) and/or with an extended scan range or manipulate samples fixed onto its sample for smooth fine-positioning (X). Further, it is stage. The closed-loop control of the probes possible to choose between the standard and and the sample allows well defined and sta- the advanced probe holder with autotouch ble positioning as well as assistance from CAD functionality and in-situ current (EBAC) amplinavigation. The system integrates into an elec- fier. tron microscope for nano-probing of i.e. 7nm transistors or into an optical microscope set- Together with partners, we can offer complete

up for atmospheric probing of large samples. nanoprobing solutions, including microscope, necessary electronics and the SMARPROBE In case the intended use is nano-probing the system. Please do not hesitate to contact us perfect choice is the **SMAR**PROBE *LX* with an for further information.

General Specifications		
Size SP8, W x L x H [mm]	187 x 187 x 56	
Size SP4, W x L x H [mm]	156 x 156 x 56	
Motion System	XYZ Closed-loop, Sample Stage and Manipulators	
Operating Environment	HV (10–7 mbar), Ambient Conditions	
Cleaning	Plasma Cleaning Compatible	
Relative Drift between Probe and Sample [nm/min]	< 1	
Thermalization Time in Vacuum [h]	< 1	
Manipulators		
Number of Manipulators	Up to 8	
Probe Mount	0.25 or 0.5 mm Diameter Tungsten Probes	
Maximum Measurement Frequency [MHz]	100	
Scan-Range in XYZ [µm]	> 10	
Leakage Current at 10 V [pA]	< 1 (with Coax, optionally with Triax available)	
Min. SEM Working Distance [mm]	2	
Sample Stage		
Scan-Range in XYZ [µm]	> 3	
Sample Mounting	SEM Stub Holder (optionally up to 4)	